

Substitute for form 1449A/PTO				<i>Complete if Known</i>	
				Application Number	Not Yet Assigned 10/719177
				Filing Date	Herewith
				First Named Inventor	Miller, David
				Art Unit	Not Yet Assigned 2834
				Examiner Name	Not Yet Assigned T. Dougherty
Sheet	1	of	3	Attorney Docket Number	019930-002840

U.S. PATENT DOCUMENTS*					
Examiner Initials*	Cite No. ¹	Document Number		Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)		
AMD	AA	5,414,540		05/09/95	Patel et al.
AMD	AB	5,917,625		06/29/99	Ogusu et al.
AMH	AC	5,999,672		12/07/99	Hunter et al.
AMH	AD	6,028,689		02/22/00	Michalicek et al.
AMH	AE	6,040,935		03/21/00	Michalicek
AMH	AF	6,097,859		08/01/00	Solgaard
AMH	AG	6,108,471		08/22/00	Zhang et al.
AMH	AH	6,128,122		10/03/00	Drake et al.
AMH	AI	09/442,061		11/16/99	Weverka, et al.
	AJ	US-			
	AK	US-			
	AL	US-			
	AM	US-			
	AN	US-			
	AO	US-			
	AP	US-			
	AQ	US-			
	AR	US-			
	AS	US-			
	AT	US-			

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)	
	AU				<input type="checkbox"/>
	AV				<input type="checkbox"/>
	AW				<input type="checkbox"/>
	AX				<input type="checkbox"/>
	AY				<input type="checkbox"/>
	AZ				<input type="checkbox"/>
	BA				<input type="checkbox"/>
	BB				<input type="checkbox"/>

Examiner Signature	<i>Thomas M. Dougherty</i>	Date Considered	3-2-05
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¹EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ² Applicant's unique citation designation number (optional). ³ Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Substitute for form 1449B/PTO				C mplete If Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	Not Yet Assigned <u>10/719177</u>
(use as many sheets as necessary)				Filing Date	Herewith
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				Examiner Name	Not Yet Assigned <u>T. Doherty</u>
Sheet <u>2</u>		of <u>3</u>	Attorney Docket Number <u>019930-002840</u>		

NON PATENT LITERATURE DOCUMENTS				
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		T ²
<u>TMB</u>	BC	T. Akiyama, et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110		
<u>TMB</u>	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978		
<u>TMB</u>	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992		
<u>TMB</u>	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96		
<u>TMB</u>	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999		
<u>TMD</u>	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100		
<u>TMD</u>	BI	V. Kaajakari et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65		
<u>TMD</u>	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987		
<u>TMD</u>	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985		
<u>TMD</u>	BL	P. Phillippe et al., "Wavelength demultiplexer: using echelle gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985		
<u>TMD</u>	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986		
<u>TMD</u>	BN	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998		
<u>TMD</u>	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202		
<u>TMD</u>	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem.Soc., Vol. 142, No. 6, June 1995		

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				Examiner Name	<i>T. Daugherty</i>
Sheet	3	of	3	Attorney Docket Number	019930-002840

NON PATENT LITERATURE DOCUMENTS				
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
<i>TMD</i>		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704		
<i>TMD</i>		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998		
<i>TMD</i>		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000		

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